US00D803075S

(12) **United States Design Patent** (10) **Patent No.: US D803,075 S**
Akao et al. (45) **Date of Patent: ** Nov. 21, 2017**

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(54) **THERMOMETRY TOOL FOR SUBSTRATE PROCESSING APPARATUS**

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(73) Assignee: **HITACHI KOKUSAI ELECTRIC INC.**, Tokyo (JP)

(**) Term: **15 Years**

(21) Appl. No.: **29/572,550**

(22) Filed: **Jul. 28, 2016**

(30) **Foreign Application Priority Data**

Feb. 10, 2016 (JP) 2016/002841

(51) **LOC (10) Cl.** **10-04**

(52) **U.S. Cl.**
USPC **D10/60**

(58) **Field of Classification Search**
USPC D10/49, 50, 51, 52, 53, 54, 55, 56, 60
CPC G01K 7/02; G01K 7/021; G01K 7/023; G01K 7/025; G01K 7/026; G01K 7/028; G01K 7/04; G01K 7/06; G01K 7/08; G01K 7/10; G01K 7/12; G01K 7/13; G01K 7/14; G01K 1/12; G01K 1/08; G01K 1/125; G01K 1/10; G01K 1/105
See application file for complete search history.

(56) **References Cited**

U.S. PATENT DOCUMENTS

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* cited by examiner

Primary Examiner — Antoine D Davis
(74) *Attorney, Agent, or Firm* — Fitch, Even, Tabin & Flannery, LLP

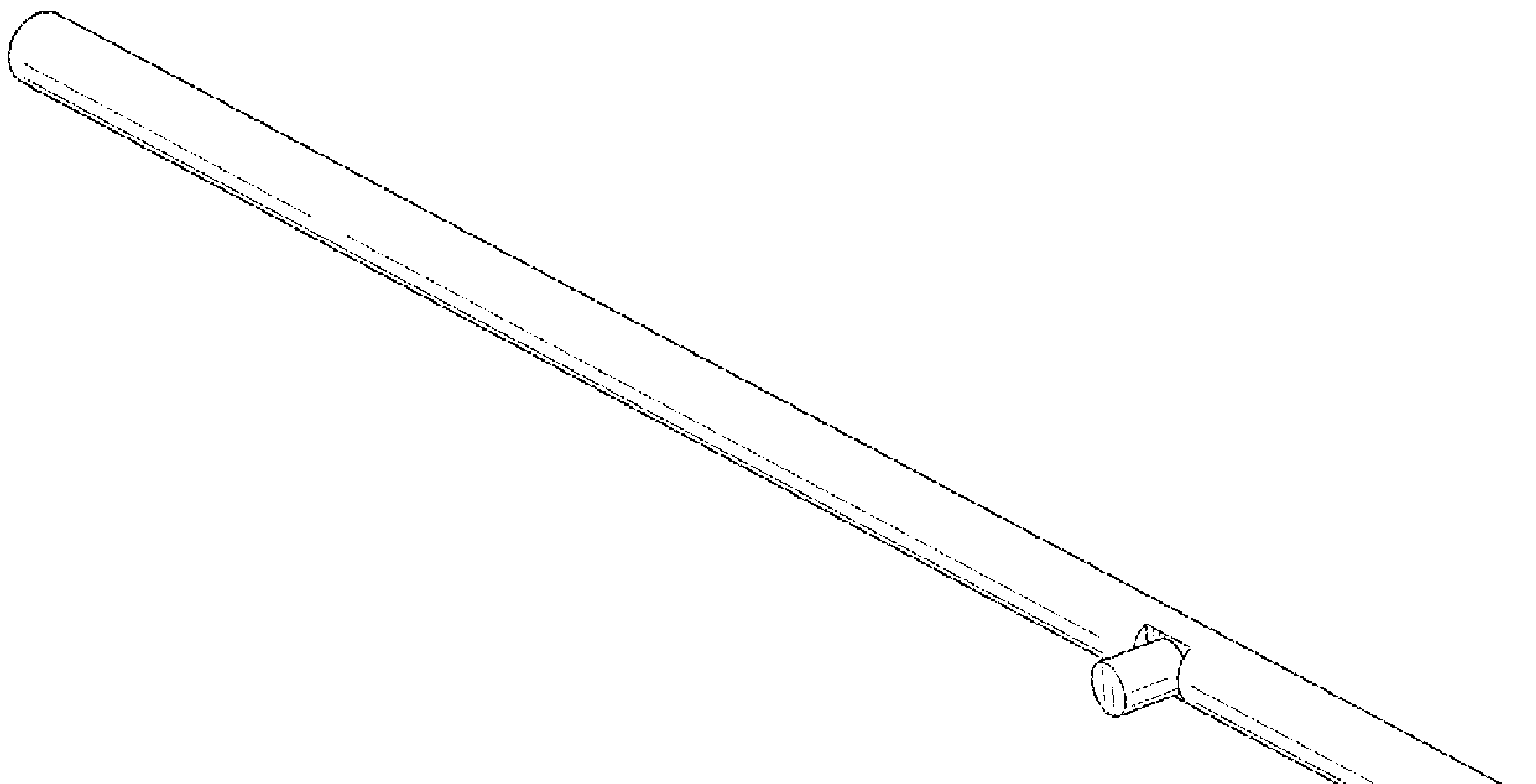
(57) **CLAIM**

We claim the ornamental design for a thermometry tool for substrate processing apparatus, as shown (and described).

DESCRIPTION

FIG. **1** is a perspective view of a thermometry tool for substrate processing apparatus showing my new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a rear elevational view thereof;
FIG. **4** is a left side elevational view thereof;
FIG. **5** is a right side elevational view thereof;
FIG. **6** is a top plan view thereof;
FIG. **7** is a bottom plan view thereof;
FIG. **8** is an enlarged portion view taken along line **8-8** in FIG. **1** thereof;
FIG. **9** is an enlarged portion view taken along line **9-9** in FIG. **2** thereof;
FIG. **10** is an enlarged portion view taken along line **10-10** in FIG. **4** thereof; and,
FIG. **11** is an enlarged portion view taken along line **11-11** in FIG. **6** thereof.
The dashed-dot-dashed lines represent the boundary lines of the claimed design.
The broken lines shown in the drawings represent portions of the thermometry tool for substrate processing apparatus that form no part of the claimed design.

1 Claim, 6 Drawing Sheets



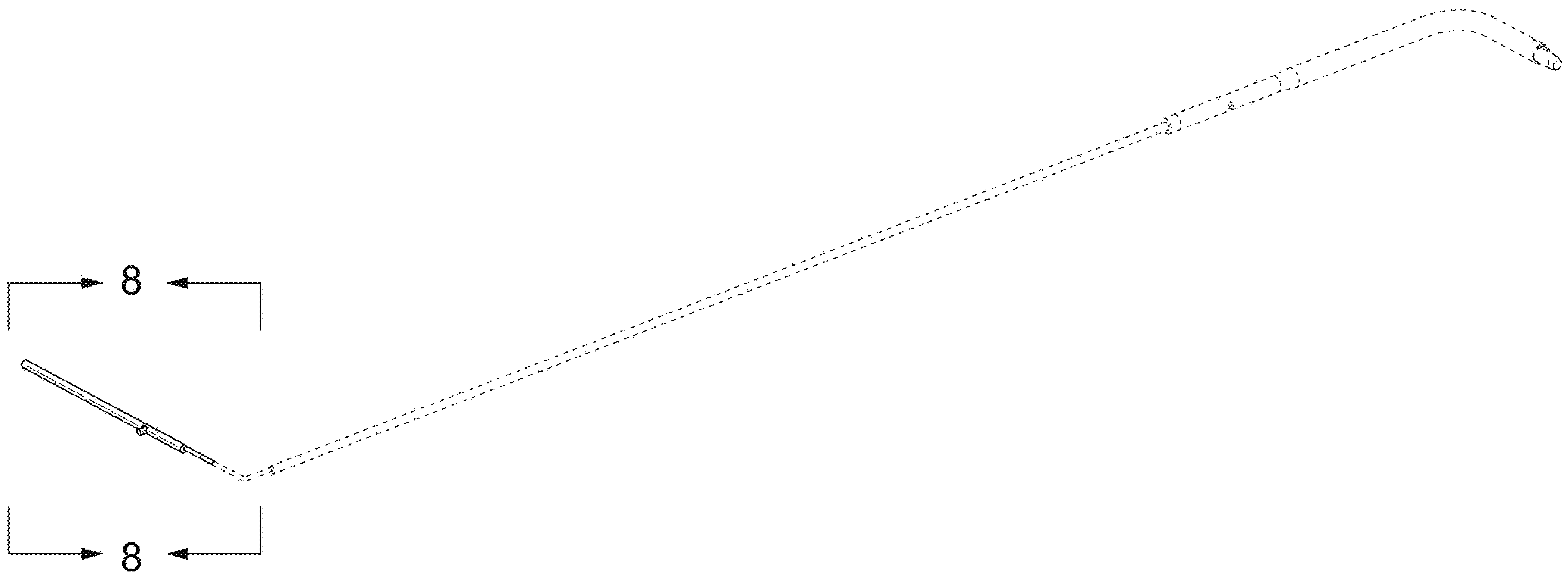


FIG. 1

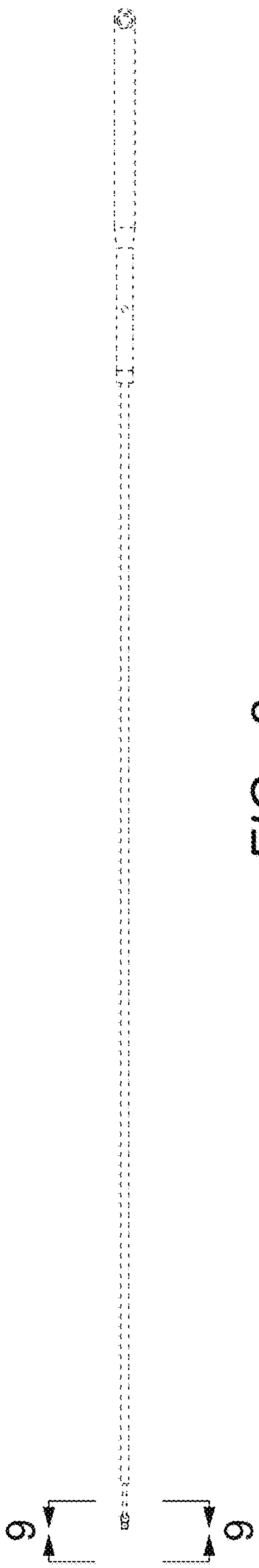


FIG. 2

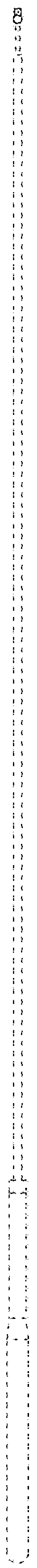


FIG. 3

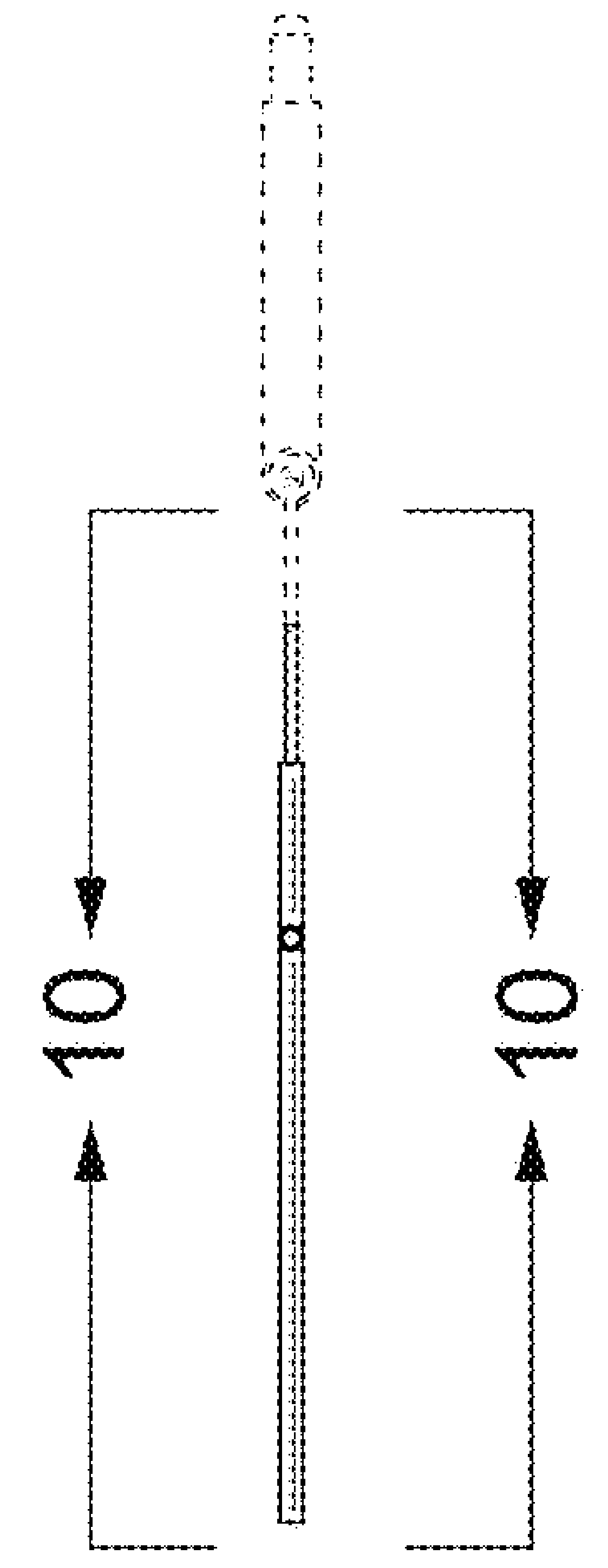


FIG. 4

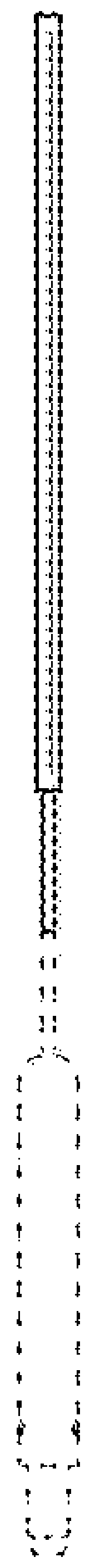


FIG. 5

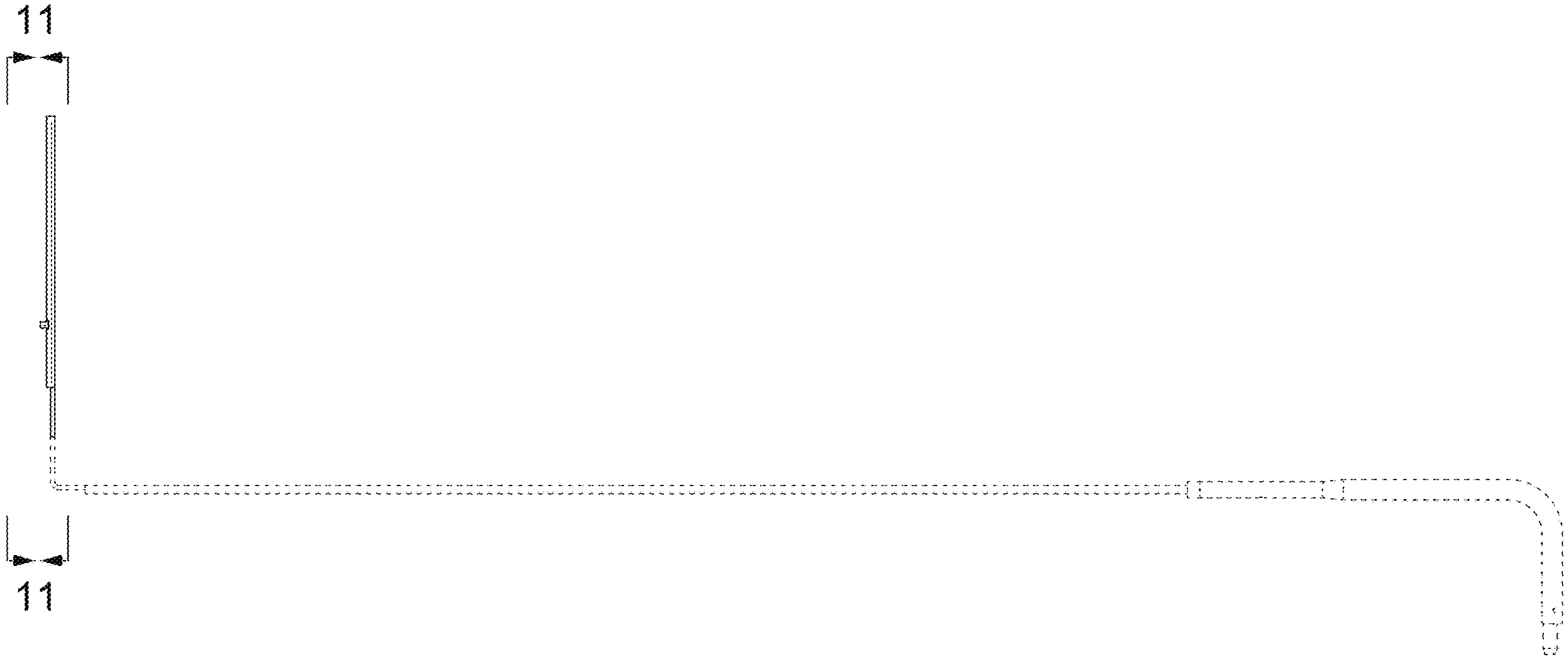


FIG. 6

FIG. 7

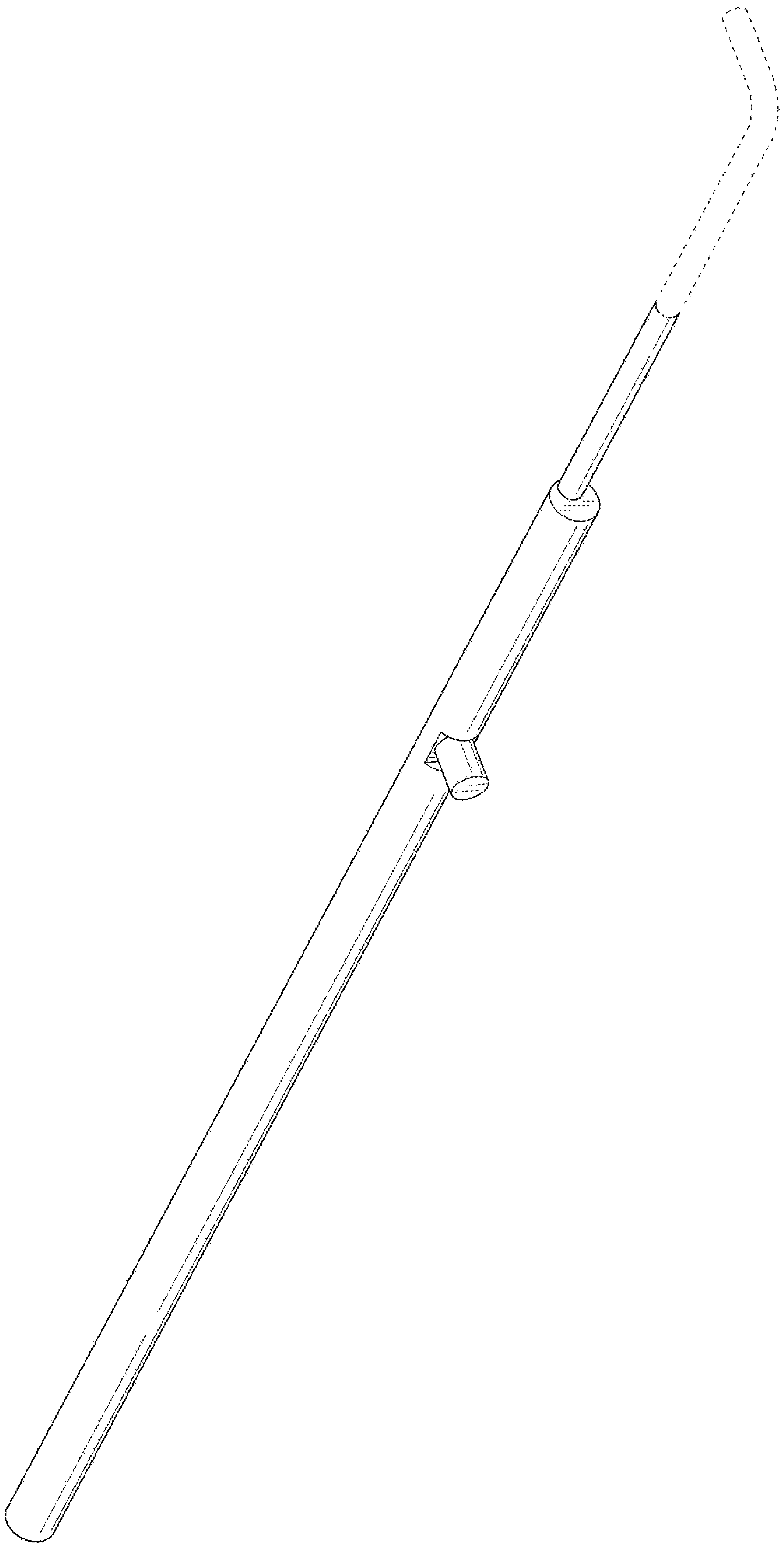


FIG. 8

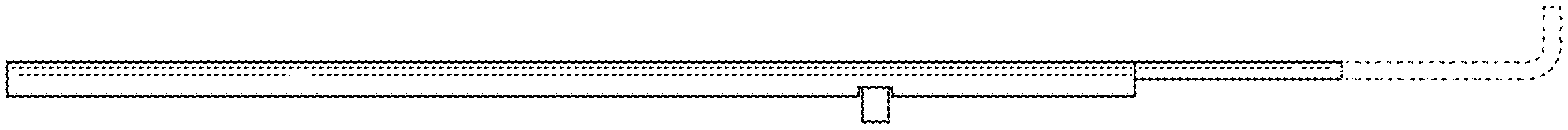


FIG. 11

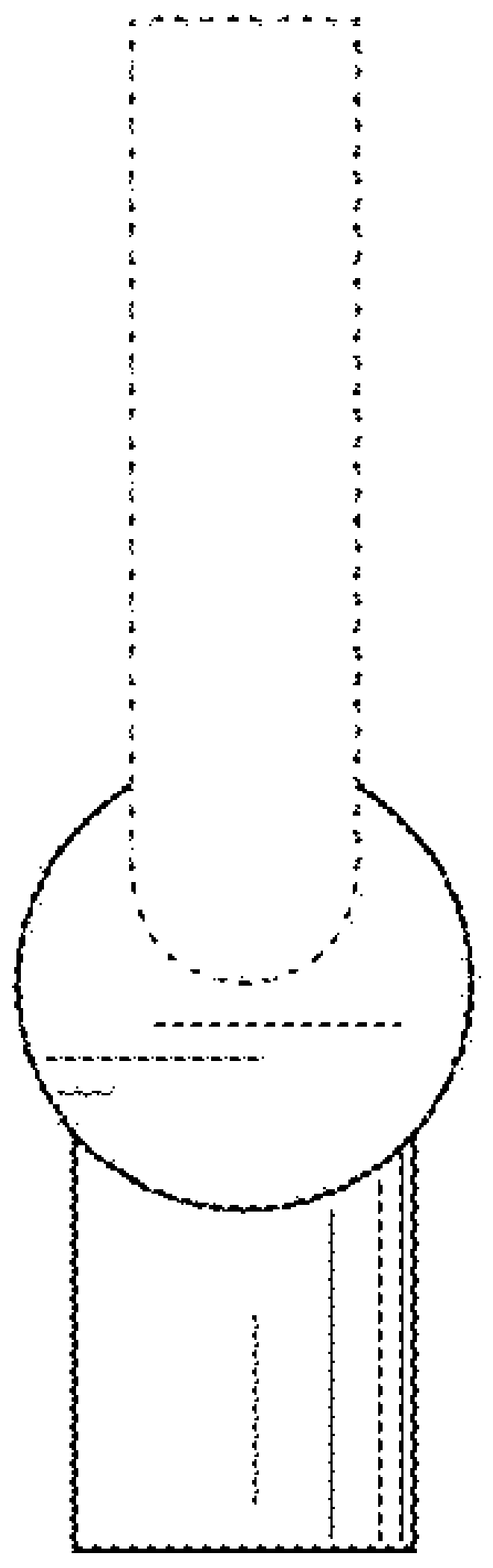


FIG. 9

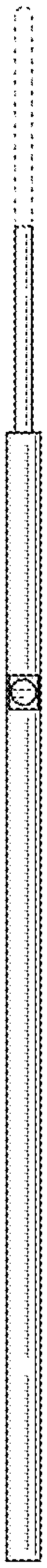


FIG. 10